

Amendments to the Specification:

Please replace the title as follows:

~~MAGNETORESISTIVE DEVICE CAPABLE OF PREVENTING A SENSE CURRENT
FROM FLOWING INTO DEAD REGIONS OF A MAGNETORESISTIVE ELEMENT,
AND THIN FILM MAGNETIC HEAD, HEAD GIMBAL ASSEMBLY AND HARD DISK
DRIVE UTILIZING THE SAME~~ METHOD OF MANUFACTURING
MAGNETORESISTIVE DEVICE CAPABLE OF PREVENTING A SENSE CURRENT
FROM FLOWING INTO DEAD REGIONS OF A MAGNETORESISTIVE ELEMENT,
AND METHOD OF MANUFACTURING THIN-FILM MAGNETIC HEAD

Please add the following paragraph between the title and the first line of text as follows:

This is a Division of Application No. 09/920,821 filed August 3, 2001. The entire disclosure of the prior application is hereby incorporated by reference herein in its entirety.

Please replace the paragraph beginning on page 14, line 20 to page 15, line 3, with the following rewritten paragraph:

In the manufacturing method, as shown in FIG. 6A and FIG. 6B, an insulating layer 2 made of an insulating material such as alumina (Al_2O_3) or silicon dioxide (SiO_2) whose thickness is 1 to 20 μm , for example, is formed through sputtering, for example, on a substrate 1 made of a ceramic material such as aluminum oxide and titanium carbide ($\text{Al}_2\text{O}_3\text{-TiC}$). On the insulating layer 2 a bottom shield layer 3 having a thickness of 0.1 to 5 μm , for example, is formed for making a read head. The bottom shield layer 3 is made of a magnetic material such as FeAlSiFeAlSi, NiFe, CoFe, CoFeNi, FeN, FeZrN, FeTaN, CoZrNb, or CoZrTa. The bottom shield layer 3 is formed through sputtering or plating.